

Customer No 25852 Attorney Docket No. 8071.0007

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:	
Takeshi MITSUISHI et al.	Group Art Unit: 2872
Application No.: 09/986,907	Examiner: Joshua Pritchett
Filed: November 13, 2001	
For: COMPOSITION FOR VAPOR DEPOSITION, METHOD FOR FORMING AN ANTIREFLECTION FILM, AND OPTICAL ELEMENT	RECE JUN-
Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 Sir:	EIVED -6 2003 Y CENTER 2800

## **REPLY**

This reply is filed in response to the non-final Office Action of March 24, 2003.

Prompt and favorable reconsideration of this application in light of the remarks below is respectfully requested.

## **REMARKS**

Claims 1-17 remain pending in this application. Applicants acknowledge, with appreciation, the indication that claims 3-8 are directed to allowable subject matter, and would be allowable if rewritten in independent form.

To the extent that claims 9-17 depend, either directly or indirectly, on the subject matter of claims 6 or 8, we believe that these claims also should have been indicated to be allowable. A process of making an antireflection film from a composition that is both

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